

EAST- [10713214.wsp:1]

File View Edit Tools Window Help

☐ Drafts  
☐ Pending  
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     L3: (177) 2 and vertical\$2  
     L4: (11) memory and vertical near nanotube\$1  
     L2: (352) memory and nanotube  
     L5: (1) ("6313503").PN.  
☐ Failed  
☐ Saved  
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☐ UDC  
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USPAT: US-PGPUB, EPO, JPO ☐ Plurals

Default operator:  ☒ Highlight all hit terms initially

memory and nanotube

	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	
156	<input type="checkbox"/>	<input type="checkbox"/>	US 20030148086 A1	20030807	15	Controlled growth of single-wall carbon nanotubes	428/293.7	423/447.3	
157	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030144185 A1	20030731	30	Cyclic peptide structures for molecular scale electronic and photonic devices	514/9		
158	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030134267 A1	20030717	11	Sensor for detecting biomolecule using carbon nanotubes	435/4	435/287.2; 435/6	
159	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030133865 A1	20030717	19	Single-wall carbon nanotube alewives, process for making, and compositions	423/447.1		
160	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030132432 A1	20030717	101	Semiconductor device	257/17	257/E29.304	
161	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030127985 A1	20030710	25	Discharge lamp	313/594		
162	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030127593 A1	20030710	41	Apparatus and method for wafer pattern inspection	250/310		
163	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030124837 A1	20030703	35	Methods of making electromechanical three-trace junction devices	438/629		
164	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030124572 A1	20030703	43	Assay electrode having immobilized lipid/protein layers, methods of making the	435/6	205/777.5; 435/7.9	
165	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030124325 A1	20030703	34	Electromechanical three-trace junction devices	428/209	174/255	
166	<input type="checkbox"/>	<input type="checkbox"/>	US 20030122133 A1	20030703	7	Semiconductor device using single carbon nanotube and method of manufacturing of	257/77		